



Primary Standards Laboratory Dimensional Standards Project

Fact Sheet

The Primary Standards Laboratory (PSL) maintains a wide variety of primary dimensional standards to assure accurate and traceable measurements for its customers. Sub-micrometer capabilities include gage blocks, roundness, thread wires, gaging balls, surface roughness, step gages, line standards, and three-dimensional measurements (see below). All primary dimensional standards are directly traceable to the Systeme International through the National Institute of Standards and Technology (NIST), other National Metrology Institutes, or to the wavelength of light. Most of the measurements listed here are accredited by the National Voluntary Laboratory Accreditation Program (NVLAP) administered by NIST.

3D artifact measurements are performed using a Leitz PMM-C-Infinity Coordinate Measuring Machine (CMM) with QUINDOS software. The CMM can measure in a $1.2\text{m} \times 1.0\text{m} \times 0.6\text{m}$ volume with a resolution of $0.004 \mu\text{m}$.

Customer short gage blocks (up to 4" or 100 mm) are measured by comparison to reference blocks using a redundant drift-eliminating design. The PSL measures its reference blocks against the wavelength of light on a Brown & Sharpe automated 2-color laser-based gage block interferometer. Customer long gage blocks are measured by comparison to reference blocks calibrated by NIST.

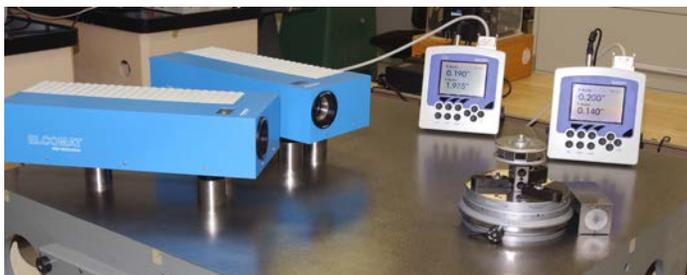


Silicon Artifact

Gage blocks, angle blocks, thread wires, gaging balls, index tables, optical polygons and squares, true squares, step gages, plain ring gages, optical flats, roundness, and surface roughness reference standards can be certified.

Dimensional Capabilities

Below is a representative sample of PSL uncertainties. The PSL is accredited by NVLAP under Lab Code 105002-0 by the National Institute of Standards and Technology/National Voluntary Laboratory Accreditation Program (NIST/NVLAP). For full details, see <http://ts.nist.gov/standards/scopes/1050020.pdf>

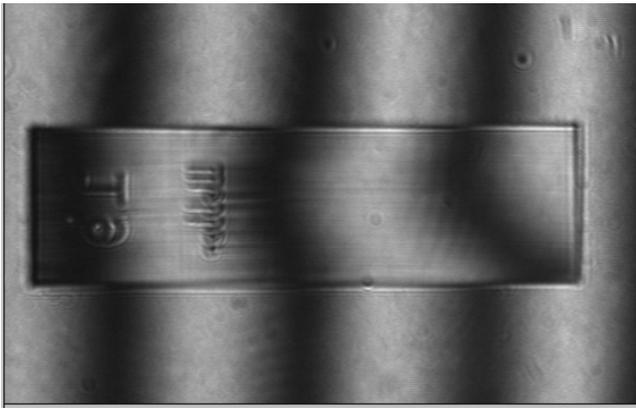


Calibration of an Optical Polygon



MEASURED PARAMETER OR DEVICE CALIBRATED	RANGE	UNCERTAINTY (k=2)	REMARKS
ANGULAR (20/D01)			
Angle Blocks Optical Squares True Squares Angular/Rotary Index Tables and Optical Polygons	30° increments 30° increments	0.50" 0.46" 0.10" 0.06" 0.50"	Standard Sizes, 1" to 45° Stack method Comparison method
GAGE BLOCKS (20/D03)			
Gage Blocks	0 mm to 100 mm 0 in to 4 in < 1 mm < 0.04 in 1 mm to 100 mm 0.04 in to 4 in 125 mm to 500 mm 5 in to 20 in	35 nm + 0.19L nm 1.4 μin + 0.19L μin 41 nm 1.6 μin 37 nm + 0.32L nm 1.5 μin + 0.32L μin 0.13μm + 0.36L nm 5.0 μin + 0.36L μin	Interferometry, Single wring Mechanical Comparison
MEASURING WIRES (20/D07)			
All Standard Thread Measuring Wires	29° and 60°	0.19 μm 7.3 μin	Comparison to NIST-calibrated Masters
OPTICAL REFERENCE PLANES (20/D08)			
Optical Reference Planes, Diameter	0 in to 10 in	30 nm 1.2 μin	Comparison to NIST-calibrated Masters, 30 nm
ROUNDNESS (20/D09)			
Roundness	0 in to 100 mm 0 in to 4 in 0 in to 350 mm 0 in to 14 in	5.4 nm + 5.1 % 0.2 μin + 5.1 % 11 nm + 6.8 % 0.42 μin + 6.8 %	Spindle error deconvolution at limited points. Spindle-compensated trace.
SPHERICAL DIAMETER; PLUG/RING GAGES (20/D11)			
Gaging Balls Calibration Spheres	1 mm to 25 mm 0.03125 in to 1 in	0.16 μm 6.3 μin	Comparison to NIST-calibrated Masters
Plain plug/ring gages	0 in to 250 mm 0 in to 10 in	94 nm + 1.1L nm 3.7 μin + 1.1L μin	
Plain ring gages	0 in to 250 mm 0 in to 10 in	0.20 μm + 0.90L nm 8.0 μin + 0.90L μin	
SURFACE TEXTURE (20/D12)			
Step Height Standards	0 μm to 50 μm	1 nm ± 1.0 % of value 0.33 μin + 0.87 %	Coherece Scanning Interferometry
Roughness Average (Ra)	0 μin to 7 μin 8 μin to 32 μin 33 μin to 150 μin	0.92 μin + 0.74 % 3.5 μin + 0.61 %	Stylus comparison with certified masters
COORDINATE MEASURING MACHINES (20/D16)			
Dimensional Gages	0 m to 1 m 0 m to 1.4 m	0.2 μm + 0.76L μm 0.34 μm + 1.2L μm	1 D 2 D





Fringes Observed by Gage Block Interferometry

Major Resources

- State-of-the-art laboratory environmental controls (as good as $\pm 0.01^\circ\text{C}$ stability and $\pm 5\%$ RH)
- Leitz PMM-C-Infinity 12-10-6 Coordinate Measuring Machine with low-force probing
- Talyrond 73HPR high-precision roundness measuring system
- Brown & Sharpe automated 2-color laser gage-block interferometer
- Elcomat HR autocollimators
- Federal 4" and 24" gage block comparators
- Laser-augmented SIP MI-6B micro-indicator
- Talysurf 6 automated surface roughness measuring system
- Taylor-Hobson CCI white light interferometer

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